

# ICP-6800 Inductively Coupled Plasma Optical Emission Spectrometer

standard



## RF Power technical parameter

- RF Power technical parameter
- Circuit type: solid-state RF power supply, with function of automatch
- Frequency: 27.12MHz±0.05%
- Frequency Stability: <0.1%
- Power Output: 800W—1200W
- Power Output Stability: <0.3%
- Escaped RF radiation: 30cm away from the instrument, electric field:  $E < 2V/m$

## Sampling System Technical Parameter

- Output working coil inner diameter : 25mm
- Torque tube: Three concentric, external diameter 20mm
- Coaxial nebulizer: Outer diameter 6mm
- Double barrel atomizing chamber: Outer diameter 34mm

## Gas Flow Controls

- Plasma Argon Flowmeter: (100-1000) L/h (1.6-16L/min)
- Auxiliary Argon Flowmeter: (10-100) L/h (0.16-1.66L/min)
- Carrier Argon Flowmeter (10-100) L/h (0.16-1.66L/min)
- Pressure Maintaining Valve (0-0.4MPa)
- Cooling Water: Temperature: 20-25°C, Rate of Flow>5L/min, Hydraulic Pressure>0.1MPa

## Spectrometer

- Optics: Czerny-Turner type
- Focal length: 1000 mm
- Grating: Ion Beam Etching Holographic Grating, 3600L/mm or 2400L/mm
- Reciprocal linear dispersion: 0.26nm/mm
- Resolution: ≤ 0.007nm (3600 line grating); ≤ 0.015nm (2400line grating)
- Wavelength range: 3600 line grating:(190nm~500) nm; 2400 line grating: (190nm~800) nm
- Minimum pace of stepping motor: ≤0.0006 nm
- Exit Slit:12μm; Entrance Slit:10μm

## Photoelectric Converter Performance

- Photomultiplier tube specification: R293/R928
- Negative HV on PMT: 0-1000V; Stability: <0.05%